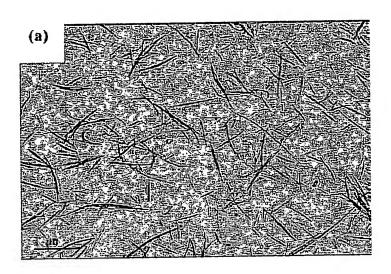
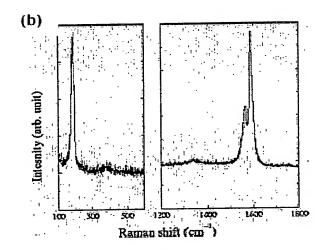
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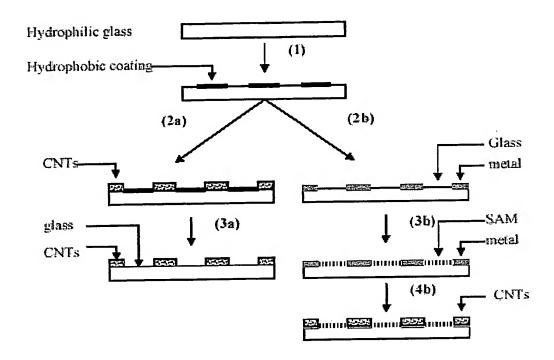
### FIGURE 1A



# FIGURE 1B



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### FIGURE 3A

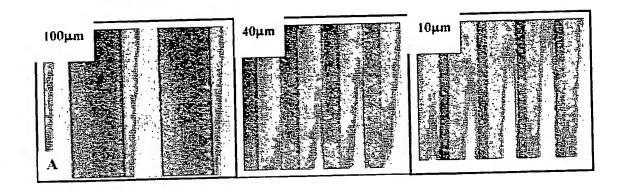
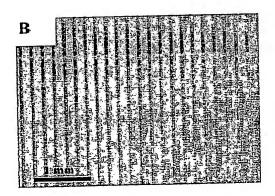
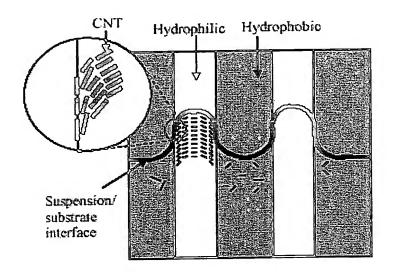


FIGURE 3B

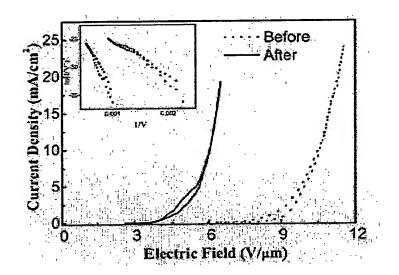


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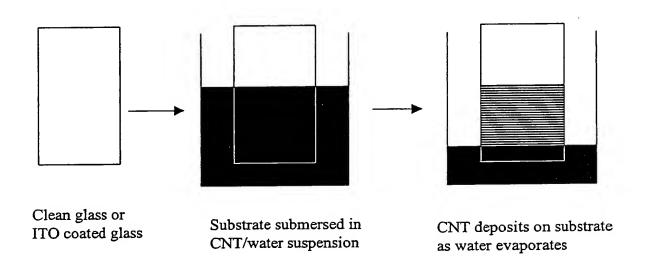


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## FIGURE 7

ITO on glass Spin coat photoresist UV lithography with mask aligned with ITO pattern develop CNT film on ITO pattern Remove photoresist

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## FIGURE 8

Glass or ITO coated glass Self assembled monolayer of OTS UV illumination in oxygen environment through photomask/mask Self assembled monolayer removed from UV illuminated area CNT deposition on SAM cleared area

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